

Interview Summary	Application N.	Applicant(s)
	09/749,926	TAKAHASHI ET AL. <i>H/H2</i>
Examiner	Art Unit	
Hung Henry V Nguyen	2851	

All participants (applicant, applicant's representative, PTO personnel):

(1) Hung Henry V Nguyen. (3) _____.

(2) Jack S. Cubert. (4) _____.

Date of Interview: 08 July 2003.

Type: a) Telephonic b) Video Conference
c) Personal [copy given to: 1) applicant 2) applicant's representative]

Exhibit shown or demonstration conducted: d) Yes e) No.
If Yes, brief description: _____.

Claim(s) discussed: Claims 1, 8, 12 and 14..

Identification of prior art discussed: Takahashi (U.S.Pat. 5,892,573).

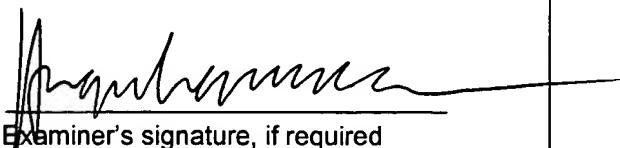
Agreement with respect to the claims f) was reached. g) was not reached. h) N/A.

Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: See Continuation Sheet.

(A fuller description, if necessary, and a copy of the amendments which the examiner agreed would render the claims allowable, if available, must be attached. Also, where no copy of the amendments that would render the claims allowable is available, a summary thereof must be attached.)

THE FORMAL WRITTEN REPLY TO THE LAST OFFICE ACTION MUST INCLUDE THE SUBSTANCE OF THE INTERVIEW. (See MPEP Section 713.04). If a reply to the last Office action has already been filed, APPLICANT IS GIVEN ONE MONTH FROM THIS INTERVIEW DATE, OR THE MAILING DATE OF THIS INTERVIEW SUMMARY FORM, WHICHEVER IS LATER, TO FILE A STATEMENT OF THE SUBSTANCE OF THE INTERVIEW. See Summary of Record of Interview requirements on reverse side or on attached sheet.

Examiner Note: You must sign this form unless it is an Attachment to a signed Office action.



Examiner's signature, if required

Continuation of Substance of Interview including description of the general nature of what was agreed to if an agreement was reached, or any other comments: Applicant submitted the proposed amendment and explained the differences between the amended claims and the invention. As to claims 1, 8 and 12, Applicant argued that while cited reference' 573 teaches using the light quantity predicted from the output of the detector (12) to determine the actual light intensity on the substrate. The detector (12) detects only changes in transmittance of the optical elements between the detector and the wafer, the present invention teaches detecting any changes in the transmittance of at least an optical element between the light source and the first detector. The Examiner respectfully disagrees with the applicant because the detector (12) also detects the change in transmittance caused by the mirror (5) and thus meets the limitations as claimed. With respect to claim 14, Applicant argued that cited reference'573 fails to teach first and second detectors at different locations for sensitive correction. The Examiner appreciates differences as explained and will carefully consider these distinctions in the next office action. .